Index, Volume 47, 1986

March

3 **A Two-Dimensional Real-Time Video Pyramid Processor**
James H. Arbeiter and Roger F. Bessler

32 **An Engineering Workstation and Video Frame-Storage Peripheral for Simulating Digital-TV Signal Processing**
Kirk A. Law and Francis S. Bernard

67 **High-Performance Al:Polymer:Al Trilayer Optical Disc II**
J. I. Gittleman, G. A. Alphonse, and Y. Arie

78 **Loop Gain Compensation in Phase-Locked Loops**
Richard Yeager

88 **Ferric Chloride Etching of Invar**
Richard B. Maynard, J. J. Moscony, and M. H. Saunders

106 **Patents**

110 **Authors**

June

117 **Process Latitude in Contrast-Enhancement-Layer Lithography**
Larry K. White and Dietrich Meyerhofer

138 **Reliability Characterization of a 3-μm CMOS/SOS Process**
M. Patrick Dugan

154 **Two-Step-Temperature Oxidation for Improved Oxide Integrity in Radiation-Hardened MOS Devices With Edge Topology**
George A. Swartz

162 **Rutherford Backscattering Spectrometry: A Quantitative Technique for Chemical and Structural Analysis of Surfaces and Thin Films**
Charles W. Magee and Lori R. Hewitt

186 **Wet-Chemical Etching of SiO_2 and PSG Films and an Etching-Induced Defect in Glass-Passivated Integrated Circuits**
Werner Kern

203 **Computerized CCD-Camera Registration Measurement Unit**
T. M. Wagner and E. C. Fox

226 **Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes**
J. R. Tower, A. D. Cope, L. E. Pellon, B. M. McCarthy, R. T. Strong, K. F. Kinnard, A. G. Moldovan, P. A. Levine, H. Elabd, D. M. Hoffman, W. M. Kramer, and R. W. Longsderff

255 **Patents**

258 **Authors**

September

271 **Motion-Detection Algorithms for Frame-Memory-Based Digital Video Processing Systems**
Hermann J. Weckenbrock

287 **Subcarrier Phase Coherence in Noise Reduction of Composite NTSC Signals—Three Approaches and Their Comparison**
Chung H. Lu

303 **Noise Reduction in Video Signals Using Pre/Post Signal Processing in a Time Division Multiplexed Component System**
A. A. Acampora, R. M. Bunting, and R. J. Petri

345 **Positive-Resist Processing for Step-and-Repeat Optical Lithography**
Lawrence K. White

380 **Characterization of Polymers by Pyrolysis Mass Spectrometry**
P. Jane Gale, Bryan L. Bentz, and William L. Harrington

398 **CMOS IIE: A Deep Drain-Extension Implant Technology for Analog/Digital ICs**
Otto H. Schade, Jr. and Robert H. Isham

429 **Patents**

433 **Authors**

December

441 **Foreword to Special Issue on Microwave Technology**
Fred Sterzer

443 **Optically Controlled Lateral PIN Diodes and Microwave Control Circuits**
Paul J. Stabile, Arye Rosen, and P. R. Herczfeld

457 **Miniature Ku-Band Low-Noise Amplifier Using Batch-Process Technology**
A. E. Fathy, P. C. Jozwiak, E. Mykietyn, V. A. Pendrick, and R. Brown

472 **Ultrastable, Low-Noise GaAs FET Oscillator With Dielectric Resonator**
G. Lan, D. Kalokitis and E. Mykietyn

487 **Analysis and Design of a 30-Way Radial Combiner for Ku-Band Applications**
A. E. Fathy and D. Kalokitis

509 **Prospects for Power from GaAs FETs at Millimeter Wave Frequencies**
G. C. Taylor and R. L. Camisa

518 **Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal**
S. G. Liu, S. Y. Narayan, C. W. Magee, C. P. Wu, F. Kolondra, J. P. Paczkowski, and D. R. Capewell

536 **Electrical Properties of n- and p-Type InP Layers Formed in Semi-Insulating InP by Ion Implantation and Thermal Anneal**
S. G. Liu, T. Bibby, S. Y. Narayan, and C. W. Magee

551 **Electrical Characterization of the Photo-Deposited SiO_2/Si Interface**
Umesh Sharma

578 **Organometallic Chemical Vapor Deposition of GaAs and AlGaAs for Microwave Applications**
R. J. Menna, S. Y. Narayan, R. T. Smith, M. S. Abrahams, and C. W. Magee

618 **High-Speed Comparators for Medium Resolution ADCs**
L. Chainulu Upadhyayula

635 **Portable Diagnostic Radiometer**
Robert W. Paglione

644 **Microwave Slip Ring for Internal Communications in Turreted Vehicles**
Robert E. Askew

655 **Patents**

659 **Authors**

671 **Index to Vol. 47, 1986**

Index to Authors, Volume 47, 1986

M. S. Abrahams Organometallic Chemical Vapor Deposition of GaAs and AlGaAs for Microwave Applications, December, p. 578
A. A. Acampora Noise Reduction in Video Signals Using Pre/Post Signal Processing in a Time Division Multiplexed Component System, September, p. 303
G. A. Alphonse High-Performance Al:Polymer:Al Trilayer Optical Disc II, March, p. 67
J. H. Arbeiter A Two-Dimensional Real-Time Video Pyramid Processor, March, p. 3
Y. Arie High-Performance Al:Polymer:Al Trilayer Optical Disc II, March, p. 67
R. E. Askew Microwave Slip Ring for Internal Communications in Turreted Vehicles, December, p. 644
B. L. Bentz Characterization of Polymers by Pyrolysis Mass Spectrometry, September, p. 380
F. S. Bernard An Engineering Workstation and Video Frame-Storage Peripheral for Simulating Digital-TV Processing, March, p. 32
R. F. Bessler A Two-Dimensional Real-Time Video Pyramid Processor, March, p. 3
T. Bibby Electrical Properties of n- and p-Type InP Layers Formed in Semi-Insulating InP by Ion Implantation and Thermal Anneal, December, p. 536
R. Brown Miniature Ku-Band Low-Noise Amplifier Using Batch-Process Technology, December, p. 457
R. M. Bunting Noise Reduction in Video Signals Using Pre/Post Signal Processing in a Time Division Multiplexed Component System, September, p. 303
R. L. Camisa Prospects for Power from GaAs FETs at Millimeter Wave Frequencies, December, p. 509
D. R. Capewell Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal, December, p. 518
A. D. Cope Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
M. P. Dugan Reliability Characterization of a 3-μm CMOS/SOS Process, June, p. 138
H. Elabd Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
A. Fathy Miniature Ku-Band Low-Noise Amplifier Using Batch-Process Technology, December, p. 457
—Analysis and Design of a 30-Way Radial Combiner for Ku-band Applications, December, p. 487
E. C. Fox Computerized CCD-Camera Registration Measurement Unit, June, p. 203
P. J. Gale Characterization of Polymers by Pyrolysis Mass Spectrometry, September, p. 380
J. I. Gittleman High-Performance Al:Polymer:Al Trilayer Optical Disc II, March, p. 67
W. L. Harrington Characterization of Polymers by Pyrolysis Mass Spectrometry, September, p. 380
P. R. Herczfeld Optically Controlled Lateral PIN Diodes and Microwave Control Circuits, December, p. 443
L. R. Hewitt Rutherford Backscattering Spectrometry: A Quantitative Technique for Chemical and Structural Analysis of Surfaces and Thin Films, June, p. 162
D. M. Hoffman Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
R. H. Isham CMOS IIE: A Deep Drain-Extension Implant Technology for Analog/Digital ICs, September, p. 398
P. C. Jozwiak Miniature Ku-Band Low-Noise Amplifier Using Batch-Process Technology, December, p. 457
D. Kalokitis Ultrastable, Low-Noise GaAs FET Oscillator With Dielectric Resonator, December, p. 472
—Analysis and Design of a 30-Way Radial Combiner for Ku-Band Applications, December, p. 487

W. Kern Wet-Chemical Etching of SiO_2 and PSG Films and an Etching-Induced Defect in Glass-Passivated Integrated Circuits, June, p. 186
K. F. Kinnard Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
F. Kolondra Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal, December, p. 518
W. M. Kramer Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
G. Lan Ultrastable, Low-Noise GaAs FET Oscillator With Dielectric Resonator, December, p. 472
K. A. Law An Engineering Workstation and Video Frame-Storage Peripheral for Simulating Digital-TV Signal Processing, March, p. 32
P. A. Levine Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
S. G. Liu Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal, December, p. 518
—Electrical Properties of n- and p-Type InP Layers Formed in Semi-Insulating InP by Ion Implantation and Thermal Anneal, December, p. 536
R. W. Longsderff Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
C. H. Lu Subcarrier Phase Coherence in Noise Reduction of Composite NTSC Signals—Three Approaches and Their Comparison, September, p. 287
C. W. Magee Rutherford Backscattering Spectrometry: A Quantitative Technique for Chemical and Structural Analysis of Surfaces and Thin Films, June, p. 162
—Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal, December, p. 518
—Electrical Properties of n- and p-Type InP Layers Formed in Semi-Insulating InP by Ion Implantation and Thermal Anneal, December, p. 536
—Organometallic Chemical Vapor Deposition of GaAs and AlGaAs for Microwave Applications, December, p. 578
R. B. Maynard Ferric Chloride Etching of Invar, March, p. 88
B. M. McCarthy Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
D. Meyerhofer Process Latitude in Contrast-Enhancement-Layer Lithography, June, p. 117
R. J. Menna Organometallic Chemical Vapor Deposition of GaAs and AlGaAs for Microwave Applications, December, p. 578
A. G. Moldovan Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
J. J. Moscony Ferric Chloride Etching of Invar, March, p. 88
E. Mykletyn Miniature Ku-Band Low-Noise Amplifier Using Batch-Process Technology, December, p. 457
—Ultrastable, Low-Noise GaAs FET Oscillator with Dielectric Resonator, December, p. 472
S. Y. Narayan Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal, December, p. 518
—Electrical Properties of n- and p-Type InP Layers Formed in Semi-Insulating InP by Ion Implantation and Thermal Anneal, December, p. 536
—Organometallic Chemical Vapor Deposition of GaAs and AlGaAs for Microwave Applications, December, p. 578
J. P. Paczkowski Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal, December, p. 518
R. W. Paglione Portable Diagnostic Radiometer, December, p. 635
L. E. Pellon Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
V. A. Pendrick Miniature Ku-Band Low-Noise Amplifier Using Batch-Process Technology, December, p. 457
R. J. Petri Noise Reduction in Video Signals Using Pre/Post Signal Processing in a Time Division Multiplexed Component System, September, p. 303
A. Rosen Optically Controlled Lateral PIN Diodes and Microwave Control, December, p. 443
M. H. Saunders Ferric Chloride Etching of Invar, March, p. 88
O. H. Schade, Jr. CMOS IIE: A Deep Drain-Extension Implant Technology for Analog/Digital ICs, September, p. 398
U. Sharma Electrical Characterization of the Photo-Deposited-SiO_2Si Interface, December, p. 551
R. T. Smith Organometallic Chemical Vapor Deposition of GaAs and AlGaAs for Microwave Applications, December, p. 578

P. J. Stabile Optically Controlled Lateral PIN Diodes and Microwave Control Circuits, December, p. 443
F. Sterzer Foreword to Special Issue on Microwave Technology, December, p. 441
R. T. Strong Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
G. A. Swartz Two-Step-Temperature Oxidation for Improved Oxide Integrity in Radiation-Hardened MOS Devices With Edge Topology, June, p. 154
G. C. Taylor Prospects for Power from GaAs FETs at Millimeter Wave Frequencies, December, p. 509
J. R. Tower Design and Performance of 4 × 5120-Element Visible and 2 × 2560-Element Shortwave Infrared Multispectral Focal Planes, June, p. 226
L. C. Upadhyayula High-Speed Comparators for Medium Resolution ADCs, December, p. 618
T. M. Wagner Computerized CCD-Camera Registration Measurement Unit, June, p. 203
H. J. Weckenbrock Motion-Detection Algorithms for Frame-Memory-Based Digital Video, September, p. 271
L. K. White Process Latitude in Contrast-Enhancement-Layer Lithography, June, p. 117
—Positive-Resist Processing for Step-and-Repeat Optical Lithography, September, p. 345
C. P. Wu Electrical Properties of $In_{0.53}Ga_{0.47}As$ Layers Formed by Ion Implantation and Rapid Thermal (Flash) Anneal, December, p. 518
R. Yeager Loop Gain Compensation in Phase-Locked Loops, March, p. 78